

UNITED STATES PATENT AND TRADEMARK OFFICE

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BEFORE THE PATENT TRIAL AND APPEAL BOARD

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MICRON TECHNOLOGY, INC.,  
INTEL CORPORATION, GLOBALFOUNDRIES U.S., INC., and  
SAMSUNG ELECTRONICS COMPANY, LTD.,  
Petitioners,

v.

DANIEL L. FLAMM,  
Patent Owner.

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PTAB Case No. IPR2017-00406<sup>1</sup>  
Patent No. 5,711,849

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**PETITIONERS' UPDATED EXHIBIT LIST**

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<sup>1</sup> Samsung Electronics Company, Ltd. was joined as a party to this proceeding via Motion for Joinder in IPR2017-01748.

### Updated Exhibit List

Exhibit #	Description
1001	U.S. Patent No. 5,711,849 (“849 Patent”)
1002	File History for U.S. Patent No. 5,711,849
1003	Declaration of Dr. David Graves (“Graves Decl.”)
1004	<i>Curriculum Vitae</i> of Dr. David Graves
1005	Alkire et al., <i>Transient Behavior during Film Removal in Diffusion-Controlled Plasma Etching</i> , J. Electrochem. Soc.: Solid-State Science and Technology, March 1985, pp. 648-656 (“Alkire”)
1006	Kao et al., <i>Analysis of Nonuniformities in the Plasma Etching of Silicon with CF<sub>4</sub>/O<sub>2</sub></i> , J. Electrochem. Soc., Vol. 137 No. 3, March 1990, pp. 954-960 (“Kao”)
1007	Galewski et al., <i>Modeling of a High Throughput Hot-Wall Reactor for Selective Epitaxial Growth of Silicon</i> , IEEE Transactions On Semiconductor Manufacturing, Vol. 5 No. 3, August 1991, pp. 169-179 (“Galewski”)
1008	Klavs F. Jensen, <i>Chemical Engineering in the Processing of Electronic and Optical Materials: A Discussion</i> , Advances in Chemical Engineering, Vol. 16, 1991, pp. 395-412 (“Jensen 1991”)
1009	Jensen et al., <i>Modeling and Analysis of Low Pressure CVD Reactors</i> , J. Electrochem. Soc., Vol. 130, No. 9, September 1983, pp. 1950-1957 (“Jensen 1983”)
1010	Hess et al., <i>Plasma-Enhanced Etching and Deposition</i> , Microelectronics Processing, Chemical Engineering Aspects, Advances in Chemistry Series 221, pp. 377-440 (“Hess”)
1011	Klavs F. Jensen, <i>Micro-Reaction Engineering Applications of Reaction Engineering to Processing of Electronic and Photonic Materials</i> , Chemical Engineering Science, Vol. 42, No. 5, 1987, pp.

	923-958 (“Jensen 1987”)
1012	U.S. Patent No. 4,918,031 (“Flamm 031”)
1013	U.S. Patent No. 5,304,282 (“Flamm 282”)
1014	U.S. Patent No. 4,815,201 (“Harris”)
1015	U.S. Patent No. 5,453,157 (“Jeng”)
1016	Petition for <i>Inter Partes</i> Review, <i>Lam Research Corp. v. Daniel L. Flamm</i> , IPR2016-00466
1017	Declaration of Mariellen F. Calter regarding Alkire et al., <i>Transient Behavior during Film Removal in Diffusion-Controlled Plasma Etching</i> (1985), Kao et al., <i>Analysis of Nonuniformities in the Plasma Etching of Silicon with CF<sub>4</sub>/O<sub>2</sub></i> (1990), and Galewski et al., <i>Modeling of a High Throughput Hot-Wall Reactor for Selective Epitaxial Growth of Silicon</i> (1992)
1018	Steinfeld et al., <i>Chemical Kinetics and Dynamics</i> , Prentice Hall, Inc., 1989
1019	Dennis M. Manos and Daniel L. Flamm, <i>Plasma Etching: An Introduction</i> , Academic Press, 1989
1020	G. B. Thomas, <i>Calculus and Analytical Geometry</i> , 4th Ed., Addison-Wesley, 1968
1021	Affidavit of Jared Bobrow in Support of Petitioner’s Motion for Admission <i>Pro Hac Vice</i>
1022	Affidavit of Chad S. Campbell in Support of Petitioners’ Motion for <i>Pro Hac Vice</i> Admission Under 37 C.F.R. §42.10(c)
1023	Reply Declaration of Dr. David Graves (“Graves Reply Decl.”)
1024	Micron’s Hearing Demonstratives

Dated: March 5, 2018

Respectfully submitted,

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## CERTIFICATE OF SERVICE

The undersigned hereby certifies that a true copy of the foregoing  
UPDATED EXHIBIT LIST has been served in its entirety this 5th Day of March,  
2018, by electronic mail on Patent Owner via its attorneys of record:

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